

S/N; 09/546,174
Docket No.: UMC-96-279 CON (JIA-462C1)
Title: HIGH DENSITY PLASMA CHEMICAL
VAPOR DEPOSITION PROCESS
Inv: Chih-Chien Liu et al.
Replacement Sheet

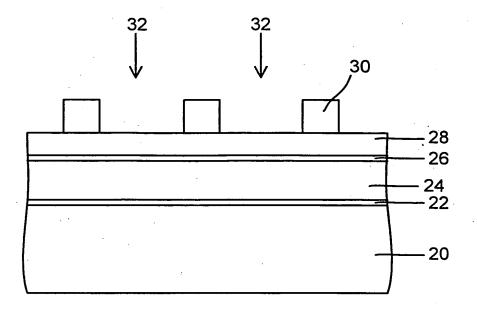


FIG. 1

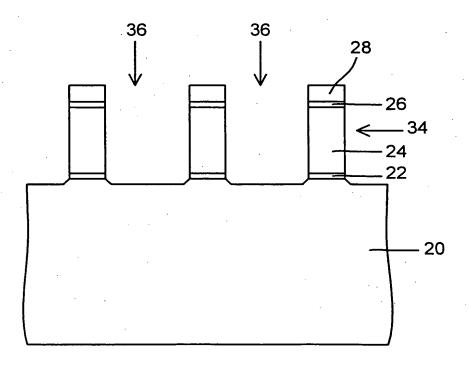


FIG. 2

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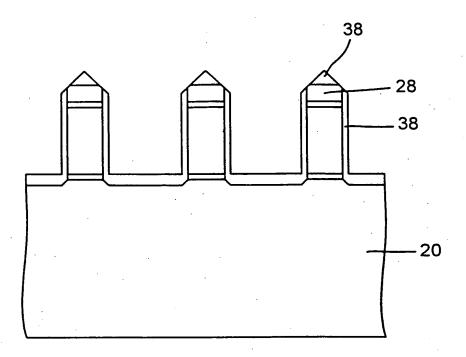


FIG. 3

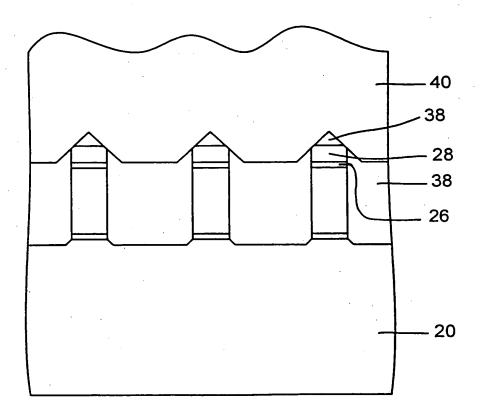


FIG. 4

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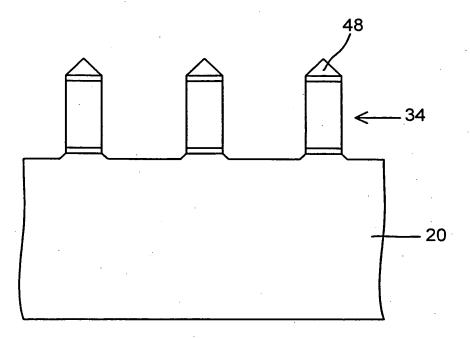


FIG. 5

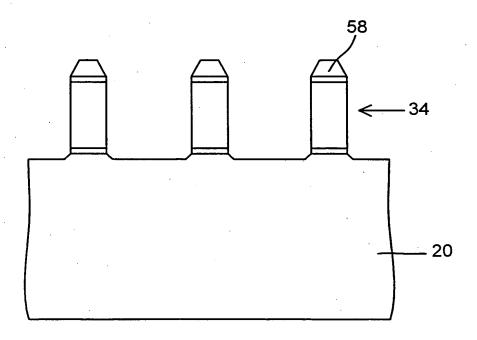


FIG. 6

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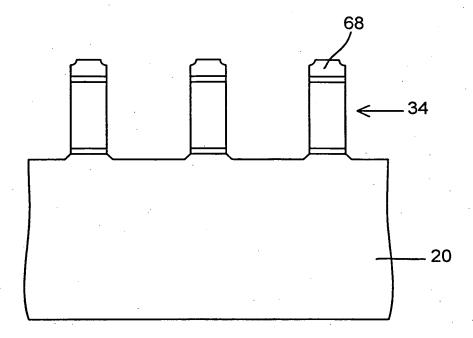


FIG. 7

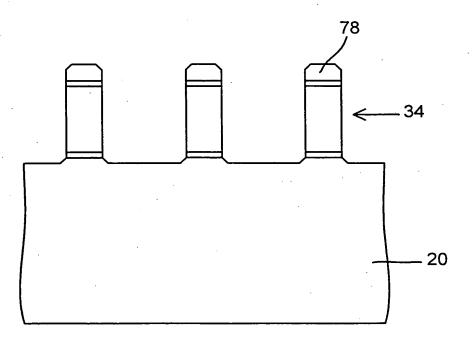


FIG. 8